KLA TENCOR Candela 8620 Configuration

Maker: KLA Tencor
Model: Candela 8620
Vintage: 2012.11

Description

- Wafer Size: 2 ~ 8 inch available (Currently 6" configured)
- Application S/W: 7.0 Build 11
- OS Version: Windows XP professional SP3
- Cassette Handling: Standard single puck with up to 200 mm cassette handler capability
- Illumination Source: Circumferential (50 mW, 405 nm), Radial (85 mW, 660 nm)

Performance

- Substrate Thickness: 380 ~ 1,300 µm
- Defect Sensitivity: 0.08 µm (PSL on bare)

Application

Defect inspection of both opaque substrates such as Si, GaAs, and InP, as well as transparent materials such as SiC, GaN, sapphire, and glass.

Utility

- Physical Dimension (W*D*H): 110 * 138 * 180 cm
- Weight Instrument: 860 lb (391 kg)
- Input Power: 115 V 12 A 50/60 Hz
- CDA: 95 ~ 110 PSI